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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on February 15, 2005.

E. R. Witt
Attorney for Applicants

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/631,134 Confirmation No.: 2470
Applicant : Hui-Chu Lin et al.
Title : METHOD FOR IMPROVING FILM
UNIFORMITY IN PLASMA ENHANCED
CHEMICAL VAPOR DEPOSITION SYSTEM
Filed : July 31, 2003
TC/A.U. : 1762
Examiner : Timothy Howard Meeks
Docket No. : 3304.2.75
Customer No. : 21552

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

Dear Sir:

This paper is filed in response to the Office Action of November 15, 2004. Please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 5 of this paper.